

ABSTRACT

In a preliminary step, information on the thickness of film deposited upon a test substrate 11 prepared for use in collecting information over a fixed irradiation time is obtained in advance while shining a laser beam LB upon a target 12 in the state in which there is a fixed positional relationship between the spatial positions of the test substrate and the point of incidence of the laser beam upon the target 12, or while shining the laser beam LB upon the target 12 while rotating the test substrate. In a main step, the deposition time at each relative positional relationship is adjusted based on the film-thickness distribution information obtained in advance in the preliminary step while spatially moving or rotating the substrate 11 or substrate holder 21 about a specific central axis of rotation relative to the point of incidence of the laser beam LB to the target 12, or while performing both said relative rotation and said relative movement.